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Attorney Docket No. UMC-96-279 CON  
Client Matter No. 81848.0016.001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Continuation Patent Application of:

Chih-Chien LIU, et al.

Serial No. 09/546,174

Filed: April 11, 2000

For: HIGH DENSITY PLASMA  
CHEMICAL VAPOR  
DEPOSITION PROCESS

Art Unit: 1711

Examiner: Rabon A. SERGENT

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PETITION FOR 1-MONTH EXTENSION

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

The undersigned hereby Petitions for a 1-month extension to extend the period for responding to the Office Action mailed November 6, 2002, from February 6, 2003 to March 6, 2003. The enclosed check for \$470.00 includes the \$110.00 1-month extension fee. Please charge Deposit Account No. 50-1123 any fee deficiency associated herewith.

Respectfully submitted,

March 6, 2003

  
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